Date Searched: 1/31/2009
Databases Searched: USPAT, USPGPUB
Plurals: ON
Terms Searched:
L1   raster$8 near10 (image or pattern or data)
L2   (fractur$3 or partition$3 or divid$3 or division or portion or section$3 or window$3 or area
or region or subarea or subregion) near15 1
L3   (multivalue$2 or multi-value$2 or values! or numbers!) near5 pixel near15 (deflect$4)
L4   2 and 3
Results: 4 hits

L5   (mask$3 or exposure or ebeam) near3 (data or pattern)
L6   (sort$3 or order$3 or priorit$8) near15 5 near15 (field or scanstrip)
L7   716/19-21.ccls. or "707"/$.ccls. or 700/117-121.ccls. or 250/492.1-492.3.ccls. or 430/4-
5.ccls. or 378/34-35.ccls.
L8   6 and 7 and @pd>20080622
Results: 4 hits

Tanner; Allen H. et al.	US 6496160 B1	USPAT 345/3.1
Adams; John A. et al.	US 5199054 A	USPAT 378/21
Latypov; Azat et al.	US 7469058 B2	USPAT 382/144

Databases Searched: EPO, JPO, IBM TDB, Derwent
Plurals: ON
Terms Searched:
L1   raster$8 near10 (image or pattern or data)
L2   (fractur$3 or partition$3 or divid$3 or division or portion or section$3 or window$3 or area
or region or subarea or subregion) near15 1
L3   (multivalue$2 or multi-value$2 or values! or numbers!) near5 pixel near15 (deflect$4)
L4   2 and 3
Results: 0 hit

Database Searched: IEE/IEEE XPlore
Terms Searched: raster* <near/10> (image or pattern or data) and (fractur* or partition* or
divid* or division or portion or section* or window* or area or region or subarea or subregion) and
(multivalue* or multi-value* or values or numbers) <near/5> pixel <near/15> deflect*

Results: Your search matched 0 of 1976242 documents

Interference Search
Database Searched: USPGPUB
Plurals: ON
Terms Searched:
L1   (raster$8 near10 (image or pattern or data)
near15 (fractur$3 or partition$3 or divid$3 or division or portion or section$3 or window$3 or area
or region or subarea or subregion) and (multivalue$2 or multi-value$2 or values! or numbers!)
near5 pixel near15 (deflect$4)).clm.
Results: 0 hit

Date Searched: 6/22/2008
Databases Searched: USPAT, USPGPUB
Plurals: ON
Terms Searched:
L1   (mask$3 or exposure or ebeam) near3 (data or pattern)

```
L2      (sort$3 or order$3 or priorit$8) near15 1 near15 (field or scanstrip)
L3      716/19-21.ccls. or "707"/$.ccls. or 700/117-121.ccls. or 250/492.1-492.3.ccls. or 430/4-
5.ccls. or 378/34-35.ccls.
L4      2 and 3
Results: 43 hits

L5      (arrang$6 or plac$6) near15 1 near15 (field or scanstrip)
L6      3 and 5
Results: 71 hits
```

Mizuno; Fumio et al.   US 6757621 B2   USPAT 702/35
Bennett; John R. et al. US 6675169 B1   USPAT 707/101
Kondo; Makoto US 6597002 B1   USPAT 250/492.2
Langston; Joseph C. et al.   US 6051344 A   USPAT 430/5
Enichen; William A. et al.   US 6040095 A   USPAT 430/5
Nakao; Shuji   US 5962172 A   USPAT 430/5
Okino; Teruaki US 5874198 A   USPAT 430/296
Manabe; Yasuo et al.   US 6350992 B1   USPAT 250/492.22
Muraki; Masato US 6104035 A   USPAT 250/492.22
Suzuki; Shohei US 6087669 A   USPAT 250/492.23
Manabe; Yasuo et al.   US 6060717 A   USPAT 250/492.22
Kusonose; Haruhiko et al.   US 5296917 A   USPAT 356/401
Frei; Joseph B. US 5189306 A   USPAT 250/492.2
Tojo; Toru et al. US 4572956 A   USPAT 250/492.2
Komatsuda, Hideki   US 20040084632 A1   US-PGPUB   250/492.2
Nakasuji; Mamoru et al. US 6194102 B1   USPAT 430/5
Sohda; Yasunari et al.   US 5387799 A   USPAT 250/492.2
Ebinuma; Ryuichi et al. US 5365561 A   USPAT 378/34
Isaacson; Michael et al. US 4659429 A   USPAT 216/24

**With rasterization:

Muraki; Masato US 6104035 A
Kusonose; Haruhiko et al.   US 5296917 A
Isaacson; Michael et al. US 4659429 A
Nakao; Shuji   US 5962172 A

Databases Searched: EPO, JPO, IBM TDB, Derwent
Plurals: ON
Terms Searched:
L1   (mask$3 or exposure or ebeam) near3 (data or pattern)
L2   (sort$3 or order$3 or priorit$8 or arrang$6 or plac$6) near15 1 near15 (field or scanstrip)
Results: 71 hits

KOYAMA, MASAAKI   JP 11087223 A
OSHIMA, TORU   JP 09162101 A
WATANABE, TAKASHI JP 06310410 A
MIYAJIMA, MASAAKI JP 04288813 A
KUSUSE, HARUHIKO et al.   JP 04237115 A
NAKASUJI M   JP 11054392 A
HOSHINO H et al.   JP 08321462 A

MANABE Y   JP 07263323 A

HAYAKAWA, YOSHIHIRO   JP 09293661 A
YODA, HARUO et al.   EP 1387389 A2

Database Searched: IEE/IEEE XPlore
Terms Searched: (mask* or exposure or ebeam) <near/3> (data or pattern) <near/15>
        (sort* or order* or priorit* or arrang* or plac*) <near/15> (field or scanstrip)

Results: Your search matched 0 of 1820465 documents